IV. REMARKS

Claims 1-11 are pending in this application. Applicants do not acquiesce in the correctness of the objections and rejections and reserve the right to present specific arguments regarding any rejected claims not specifically addressed. Further, Applicants reserve the right to pursue the full scope of the subject matter of the original claims in a subsequent patent application that claims priority to the instant application. Reconsideration in view of the above amendments and following remarks is respectfully requested.

Entry of this Amendment is proper under 37 C.F.R. §1.116(b) because the Amendment:

(a) places the application in condition for allowance as discussed below; (b) does not raise any new issues requiring further search and/or consideration; and (c) places the application in better form for appeal. Accordingly, Applicants respectfully request entry of this Amendment.

Applicants note that the pending claims are incorrectly cited on the Office Action summary as 1-10, rather than 1-11. Correction is requested.

With regard to the Office's statement regarding the improper listing of references, Applicants believe that Information Disclosure Statements (IDS) for all references listed were submitted. In particular, an IDS for non-patent references was submitted on 12/16/02 and initialed by the Office. In addition, an electronic IDS for US patents was submitted with the application. Clarification as to which references have not been properly cited is respectfully requested.

In the Office Action, the specification was objected to because of informalities. By this amendment, the specification has been amended to correct the typographical error. Accordingly, Applicants request withdrawal of the rejection.

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In the Office Action, claim 6 was rejected under 35 U.S.C. §102(b) as being anticipated by Yamaguchi et al., Process and Device Optimization of an Analog Complementary Bipolar IC Technology With 5.5-GHz fT PNP Transistors, hereinafter "Yamaguchi et al.;" claims 1-3, 5, 7 and 9 were rejected under 35 U.S.C. 103(a) over Yamaguchi et al. and Babcock et al. (U.S. Publication No. 2003/0080394), hereinafter "Babcock et al.;" claim 4 was rejected under 35 U.S.C. 103(a) over Yamaguchi et al. in view of Babcock et al. and Goth (U.S. Patent No. 4,719,185), hereinafter "Goth;" and claim 8 was rejected under 35 U.S.C. 103(a) over Yamaguchi et al., in view of Babcock et al. and Harame et al. (U.S. Patent No. 4,997,776), hereinafter "Harame et al.;" and claim 11 was rejected under 35 U.S.C. 103(a) over Yamaguchi et al. in view of Goth. Applicants submit that the pending claims are allowable and thus respectfully request withdrawal of the rejections.

With respect to claim 6, Yamaguchi et al. fail to disclose each and every claimed feature. The present invention recites, inter alia, "a single layer of silicon that forms an emitter region of the PNP transistor, an extrinsic base region of the NPN transistor and an intrinsic base region of the NPN transistor." First, Applicants submit that Yamaguchi et al. only mention P⁺ (or N⁺) implants for PNP collector contact and NPN extrinsic base region and there is no mention of a single layer that forms emitter region of PNP transistors and extrinsic and intrinsic base region of NPN transistors.

Second, although Yamaguchi et al. mention sharing collector contact implants for the PNP transistors with a P^+ extrinsic base implant for the NPN transistors (Yamaguchi et al. at 1023 –24; Fig. 1), they do not disclose the same regarding the emitter region of the PNP

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transistor. In Yamaguchi et al, the PNP collector contact is specifically distinguished with the PNP emitter region. (See Fig. 1, the collector being marked as "c" and the emitter being marked as "c"). In contrast, the present invention discloses, inter alia, "a single layer of silicon that forms an emitter region of the PNP transistor, an extrinsic base region of the NPN transistor[.]"

Third, Yamaguchi et al. do not disclose sharing collector contact implants for PNP transistors with a P⁺ intrinsic base implant for NPN transistors. In Yamaguchi et al., the NPN extrinsic base implant masks and the intrinsic base implant masks are listed together, but only the elimination of the PNP extrinsic base implant masks is specifically disclosed, which indicates that Yamaguchi et al. do not anticipate the elimination of NPN intrinsic base implant masks. In other words, Yamaguchi et al. do not anticipate sharing the intrinsic base regions implants for the NPN transistors with the collector contact implants for the PNP transistors. See Yamaguchi et al. at 1020. So even if the implants of P⁺ are taken as equal to a "layer," in Yamaguchi et al., the collector contact of the PNP is not formed on the same layer as the intrinsic base region of the NPN transistor because they are not formed by the same implant of P⁺. In view of the foregoing, Yamaguchi et al. do not disclose "a single layer of silicon that forms an emitter region of the PNP transistor, ... and an intrinsic base region of the NPN transistor[,]" as recited in claim 6. Accordingly, claim 6 of the present invention is not anticipated by Yamaguchi et al. Applicants respectfully request withdrawal of the rejections.

With respect to claim 1, Applicants submit that there is no suggestion or motivation to combine Yamaguichi et al. and Babcock et al. In Babcock et al., carbon or other cabon-bearing species such as SiGeC is used to retard the diffusion of the common P-type dopant, e.g., boron, and common n-type dopant. Note Page 3, Paragraph 0034. Retarding diffusion of P-type dopant

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is not a concern in Yamaguchi et al. Therefore, it is incomprehensible why a person having ordinary skill in the art would modify Yamaguchi et al. to incorporate Babcock et al.

In addition, even if Yamaguchi et al. and Babcock et al. are combined, the combination does not disclose or suggest each and every claimed feature of claim 1. Similar to the analysis regarding claim 6, Yamaguchi et al. do not disclose or suggest, inter alia, "an intrinsic base region of the vertical NPN transistor located in the same layer as the emitter region of the vertical PNP transistor[,]" as recited in claim 1. Babcock et al. do not overcome this deficiency of Yamaguchi et al. Moreover, Babcock et al. do not disclose or suggest the claimed invention including "an emitter region of the vertical PNP transistor including silicon and germanium[,]" as recited in claim 1. What Babcock et al. disclose is "carbon-bearing species such as SiGeC" included in emitter polysilicon layer (35) to retard diffusion of p-type dopant from the emitter polysilicon layer (35) to the active emitter region (40). See Abstract and Paragraph 42. In Babcock et al., there is no disclosure or suggestion of germanium in the active emitter region (40). Therefore, Babcock et al. do not disclose or suggest "an emitter region of the vertical PNP transistor including silicon and germanium." Yamaguchi et al. do not overcome this deficiency of Babcock et al. Accordingly, Applicants respectfully request withdrawal of the rejections.

Claims 2-5 are dependent upon claim 1 and claims 7-11 are dependent upon claim 6.

Applicants submit that those dependent claims are allowable for the same reasons stated above, as well as for their own additional features.

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Applicants respectfully submit that the application is in condition for allowance. Should the Examiner believe that anything further is necessary to place the application in better condition for allowance, he is requested to contact Applicant's undersigned attorney at the telephone number listed below.

Respectfully submitted,

Sankall

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